

35.C15381

PATENT APPLICATION

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J1017 U.S. PTO  
09/865549  
05/29/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: Examiner: NYA  
TAKAHARU KONDO ET AL. )  
: Group Art Unit: NYA  
Appln. No.: NYA )  
:  
Filed: Herewith )  
:  
For: METHOD OF FORMING SILI- )  
CON-BASED THIN FILM, SI- :  
LICON-BASED THIN FILM AND)  
PHOTOVOLTAIC ELEMENT : May 25, 2001

Commissioner for Patents  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

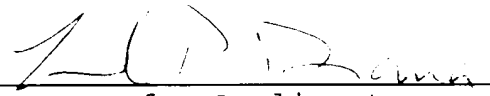
Sir:

In compliance with the duty of disclosure under  
37 C.F.R. § 1.56 and in accordance with the practice under  
37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is  
directed to the documents listed on the enclosed Form PTO-  
1449. Copies of the listed documents are also enclosed.

It is respectfully requested that the above  
information be considered by the Examiner and that a copy of  
the enclosed Form PTO-1449 be returned indicating that such  
information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,

  
Attorney for Applicants

Registration No. 6925

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